



**PATENT APPLICATION**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of

Docket No: Q76605

Takayasu KOMATSU, et al.

Appln. No.: 10/621,382

Group Art Unit: 1756

Confirmation No.: 4041

Examiner: Nicole M. Barreca

Filed: July 18, 2003

For: ETCHING SUBSTRATE MATERIAL, ETCHING PROCESS, AND ARTICLE  
OBTAINED BY ETCHING

**AMENDMENT UNDER 37 C.F.R. § 1.111**

**MAIL STOP AMENDMENT**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated May 20, 2005, please amend the above-identified application as follows on the accompanying pages.

**TABLE OF CONTENTS**

AMENDMENTS TO THE CLAIMS .....	2
REMARKS .....	4